

# XFEL0、最近の話題

羽島 良一

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ERLビームダイナミクスWG

# 3次高調波によるXFELO

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PHYSICAL REVIEW LETTERS

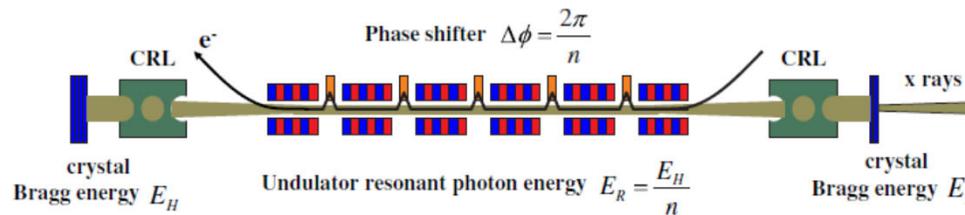
week ending  
20 JANUARY 2012

## Proposal for an X-Ray Free Electron Laser Oscillator with Intermediate Energy Electron Beam

Jinhua Dai, Haixiao Deng,\* and Zhimin Dai

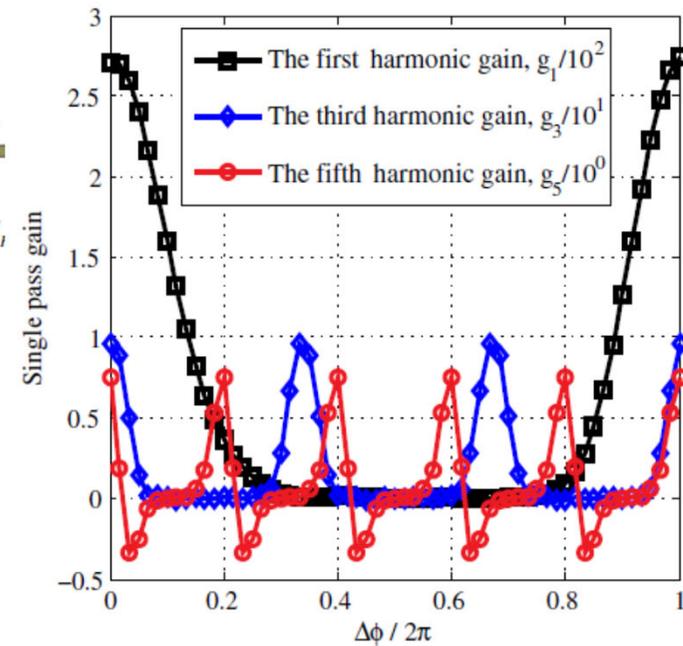
Shanghai Institute of Applied Physics, Chinese Academy of Sciences, Shanghai, 201800, China

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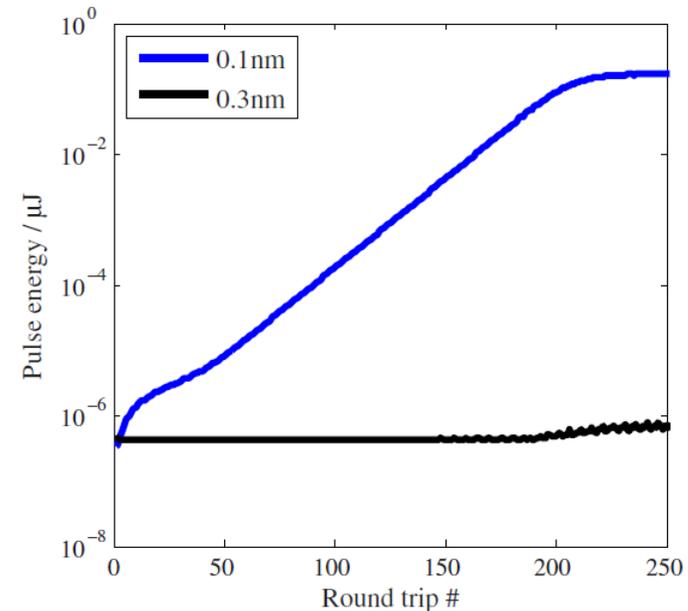
3.5 GeV electron で 12keV のXFELO を発振

アンジュレータ間の位相シフトで基本波の発振を抑制し、3次高調波のみを発振する



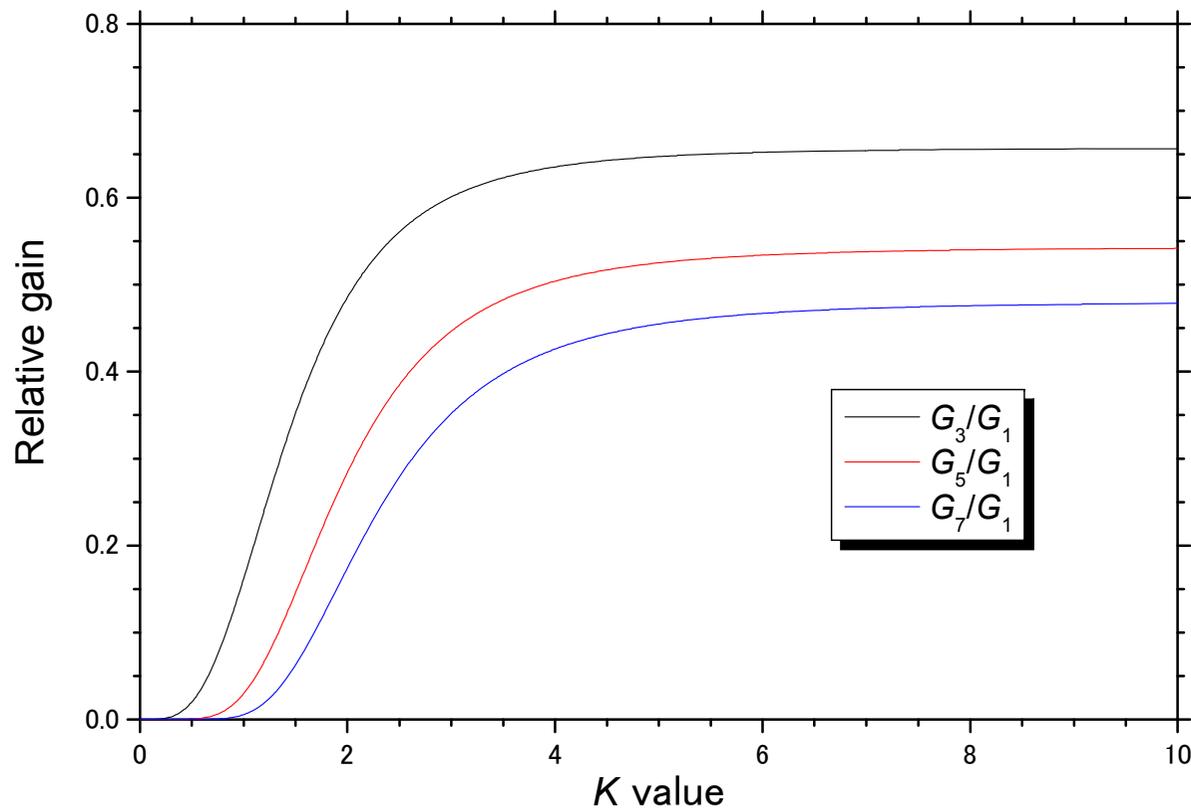
# 3次高調波によるXFEL

Parameters	Third harmonic	Fifth harmonic
Crystal Bragg energy $E_H$	12.42 keV	20.71 keV
Phase jump $\Delta\varphi$	$4\pi/3$	$6\pi/5$
Undulator period $\lambda_u$	15 mm	15 mm
Undulator number $N_u$	1200	1200
Undulator parameter $K$	1.3244	1.3244
Beam energy $E$	3.5 GeV	3.5 GeV
Slice energy spread $\sigma$	100 keV	100 keV
Beam peak current $I$	20 A	100 A
Slice emittance $\varepsilon_n$	$0.083 \mu\text{m-rad}$	$0.083 \mu\text{m-rad}$
Single-pass gain $g_h$	65%	72%
Total cavity reflection $r$	80%	80%
Cavity length $L_c$	150 m	150 m
Bragg crystal	C(4,4,4)	C(5,5,9)
FWHM spectral width	5.5 meV	24.6 meV
FWHM temporal width	463 fs	107 fs
Photons/pulse	$0.86 \times 10^8$	$0.24 \times 10^8$
Output peak power	0.35 MW	0.74 MW



# 高調波のゲイン計算

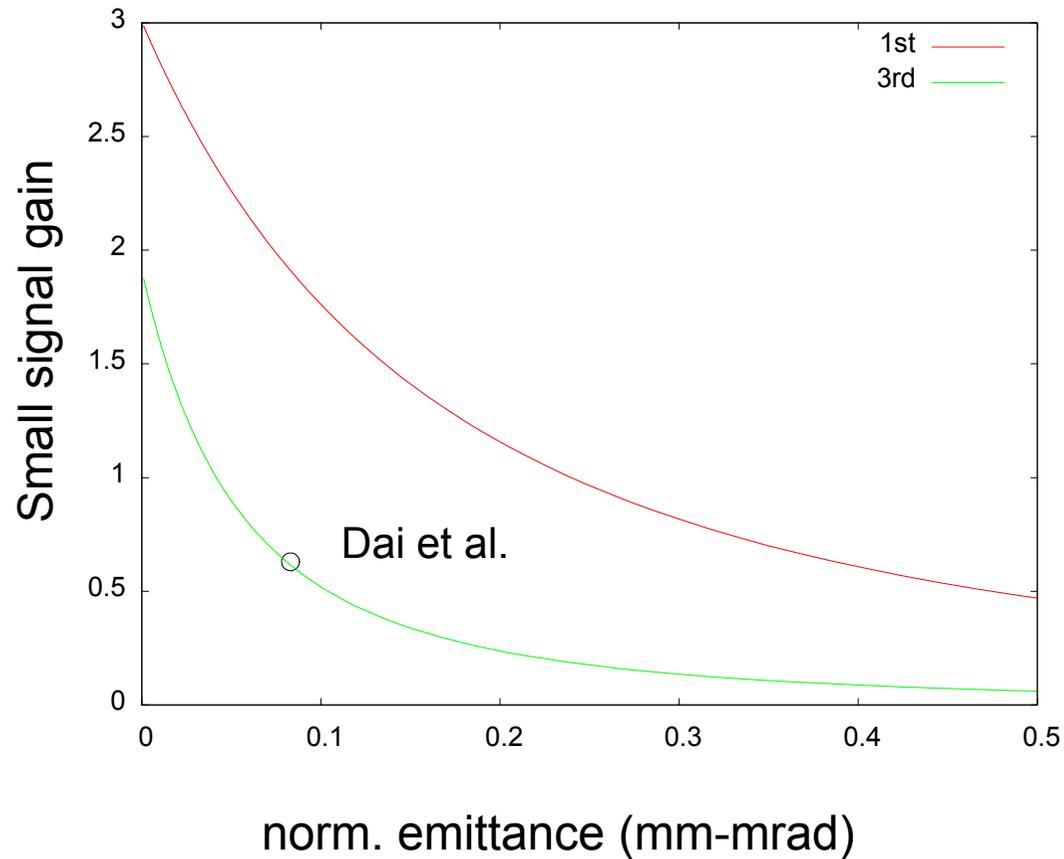
産総研、清さんによる



$$G_n = n \frac{[JJ]_n^2}{[JJ]_1^2} G_1$$

Filling factor (エミッタンス)、  
エネルギー広がりの効果を  
別途加える。

# 解析式によるゲインの確認



beta = 20m とすると  
Dai et al. 論文のゲインを  
ほぼ再現した。

	Kim et al.	Hajima et al.	Dai et al.
E (GeV)	7	5	3.5
$\epsilon_n$ (mm-mrad)	0.082	0.13	0.083
$\sigma_E$ (keV)	1400	250	100
charge	19	7.7	20
$\sigma_t$ (ps)	2	0.38	(0.40)
$I_p$ (A)	-	-	20
Undulator pitch (mm)	18.8	14.3	15
Undulator period	3000	3000	1200
Undulator K	1.414	0.8344	1.3244
*Gap (mm)	(5)	(5)	(3.25)
Gain (%)	26	40	65
X-ray Bandwidth (meV)	2.3	-	5.5
Length (fs)	850	510	463
Photon/pulse	$10^9$	$0.7 \times 10^8$	$0.86 \times 10^8$

すべて 12keV (1 Å)

\*Gap → Halbach type を仮定したとき

# K-J. Kim 氏からの問い合わせ

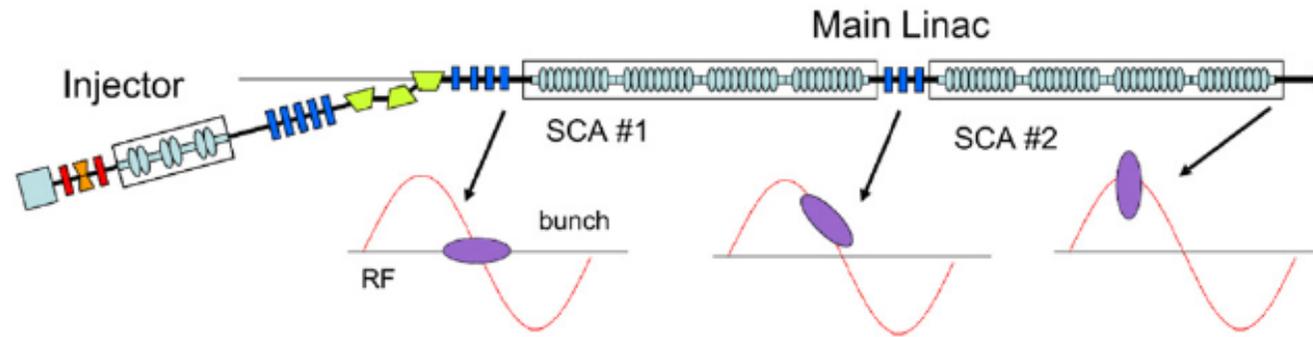
The question is whether you can produce and accelerate such beams. If yes, the beam is suitable for an XFEL, possibly with >100 MHz rep rate, with high average brightness.

Kwang-Je

- > the gain calculation I did was for our "nominal" beam and undulator parameters ( $E=7$  GeV,  $N_u = 3000$ , etc.) with the following changes:
  - > Charge = 1.0 pC
  - > Length = 0.25 ps ( $I = 1.6$  A)
  - > emittance = 0.062 mm\*mrad [per Rosenzweig et. al.'s NIMA 593, 39 (2008)]
  - > energy spread = 100 keV
  - >
  - > I find that the gain is maximized at 0.5 when  $Z_R = Z_{\beta\text{beta}} = 14$  m.
  - >
  - > If I increase the energy spread to 250 keV the gain is 0.4.

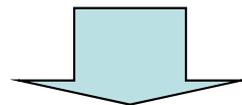
# ERL injector and velocity bunching

R. Hajima et al. / Nuclear Instruments and Methods in Physics Research A 637 (2011) S37–S42



Parameters of electron bunch at the end of the main linac are bunch charge 7.7 pC, energy 27.7 MeV, rms bunch length  $\sigma_t=380$  fs, rms energy spread  $\sigma_E=250$  keV, rms normalized emittance  $\varepsilon_x=0.16$  mm-mrad, and  $\varepsilon_y=0.13$  mm-mrad. The energy

7.7 pC, 380 fs, 0.16 mm-mrad, 250 keV



??? 1 pC, 250 fs, 0.062 mm-mrad, 100 keV ???

ビームダイナミクス以外の検討=ビームモニタ?